

Notice of References Cited	Application/Control No. 10/709,054	Applicant(s)/Patent Under Reexamination CHANG ET AL.	
	Examiner Eric B. Chen	Art Unit 1765	Page 1 of 1

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*	A	US-4,787,997	11-1988	Saito et al.	252/79.4
*	B	US-6,275,293	08-2001	Brown, Timothy L.	356/600
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	M	US-			

FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

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	U	Kern, Handbook of Semiconductor Wafer Cleaning Technology, 1993, Noyes Publications, pp. 123, 125-126.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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